# LithOptek MIGRA

# Lithoptek muara

## Introducing CDOP: The CD Optimizer

Making Systematic CD Errors A Thing of the Past

## CDOP is the 1<sup>st</sup> 200mm Industry Solution to Offer ALL these benefits

**Corrects:** • Systematic CD errors across the wafer

- CDs to target with nanometer precision
- Both global and in-die errors
- CD errors from ALL sources: Litho, Etch, CMP, . . . etc.

Each wafer pixel (0.5 × 0.5 mm) is given a unique correction CD correction at 125,000 locations at 120 WPH!

CD control as good as your metrology

## LithOptek CD Optimizer Available NOW



- Compact footprint & advanced robotics by Milara
- Dual-cassette load port with automatic wafer size detection (100, 150, 200 mm)
- Supports notch/flat, OCR, Si/SiC/glass wafers, etc.
- Easy-to-use interface

## LithOptek CD Optimizer Available NOW



- Uses simple process recipes built from CD-SEM data and resist properties
- Fully tested at MIT Lincoln Laboratory
  200 mm Fab
- Ready for High Volume Manufacturing
- Global support provided by Milara-LithOptek partnership

## LithOptek CD Optimizer Available NOW



Imagine eliminating CD Variations in your Fab

#### LithOptek CD Optimizer

#### Easy-to-use Recipe Builder Software

#### CD error map



#### Recipe Builder



#### Recipe File



#### CDOP Exposure



#### **CDOP Recipe Example**



#### Impossible! How does it work?

Traditional lithography results in a narrow gray zone between fully exposed and unexposed regions, the CDOP utilizes the gray zone

- CDOP adds a small tailored deep-UV trim dose to each pixel
- Gray zone areas are slightly shifted to smaller CD to hit target

LithOptek's Gray Zone strategy delivers results!



Cross section of simulated exposure dose

## LithOptek CD Optimizer

# Robotics by

A Collaboration of Technical Expertise Bringing Tools to Market Quickly

#### **MILARA Handler Tool Interface**



Powerful and Easy to use!

#### **MIGRA Handler Tool Interface**



- Touch screen controls
- Process animation
- Tool config management
- Process recipe library
- Recipe support: Per-slot and per-cassette
- Manual and automatic recipe modes

## **MIGRA Handler Tool Interface**



- Robot and Process chamber cameras
- Automatic process monitor, self calibration, logging, and much more . . .

#### **Optional:**

Remote operation, SECS/GEM capable

#### **MIARA Global Service Network**

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Headquarters Milford, MA USA

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#### **Branch Offices**

European Office Plovdiv, Bulgaria

China Office Beijing, China Shanghai, China Manufacturing Milford, MA USA Plovdiv, Bulgaria Sales Milford, MA USA Plovdiv, Bulgaria Beijing, China Support

Milford, MA USA USA West Coast Plovdiv, Bulgaria Israel Singapore Dongguan, China Shanghai, China Suzhou, China Taoyuan, Taiwan

#### Case Study: CDOP Correction

#### CD Correction of 100 nm L/S pattern flattened to 55 nm target

#### After litho (193 nm)



2.07 nm STD

#### After etch (no CDOP)



#### After CDOP + etch



#### 8.42 nm STD

2.11 nm STD

> 3X reduction of CD variation!

## **CDOP Testing & Demonstration**

#### > 3X reduction of CD variation!

## **CDOP Testing & Demonstration**

#### Available NOW

## **CDOP Testing & Demonstration**

Interested customers can run test wafers on our CDOP tool at MIT Lincoln Laboratory's fully-equipped 200mm Microelectronics facility.

The Microelectronics Laboratory is a state-of-the-art semiconductor research and fabrication facility that supports the design, fabrication, and packaging of novel devices.





LL MIT - Microelectronics Laboratory facility Lexington, MA

#### Check Out CDOP: the CD Optimizer

#### Join Us in the Fight to Eliminate CD Variations . . .

one wafer at a time

# LithOptek MIARA

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